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Semiconductor Process and Yield Analysis Integrated Real-time Management Method

Appl. No.

10/708,277

Confirmation No. 2276

Applicant

Hung-En Tai,

Chien-Chung Chen,

Sheng-Jen Wang

Filed

February 20, 2004

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Examiner

GARLAND, STEVEN R

Docket No.

LKSP0045USA0

Customer No.

27765

Commissioner for Patents

P.O. Box 1450

Alexandria VA 22313-1450

AMENDMENT

5 Sir:

In response to the Office action of February 08, 2006, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of

10 this paper.

Remarks/Arguments begin on page 7 of this paper.